

a cassette load station;
a load lock chamber, said load lock chamber comprising a double dual slot load lock constructed at a same location; wherein each of said dual slot load locks further comprises a heating plate and a cooling plate, said heating plate and said cooling plate located in different slots of said dual slot load lock;

A1
a transfer chamber, wherein said transfer chamber is centrally located; and

one or more process chambers, wherein said process chambers are located about the periphery of said transfer chamber.

Please amend claim 4 to read as follows:

X2
4. (amended) The substrate processing system of claim 1, wherein said heating plate is a stationary plate or a moving plate.

Please amend claim 6 to read as follows:

X3
6. (amended) The substrate processing system of claim 1, wherein said heating plate heats up to a temperature of about 400°C.